

IN THE CLAIMS:

Please cancel Claims 1-5 without prejudice.

Please add the following newly drafted Claims 7-12:

7. A microelectromechanical system (MEMS) device including a diaphragm comprising a conducting surface, the MEMS device further comprising exactly one layer of C₆₀ fullerene on the conducting surface.
8. The MEMS device of claim 7, wherein the conducting surface includes gold.
9. The MEMS device of claim 8, where the C₆₀ fullerene is deposited on the gold surface by sublimation.
10. The MEMS device of claim 8 where the C₆₀ fullerene is deposited on the gold surface by chemisorbtion.
11. The MEMS device of claim 7 further comprising a single event pipe containing a gas that reacts with carbon byproducts.
12. A mechanically adjustable electron tunneling tip system comprising:
a tunneling tip including a piezoelectric element connected to an end of the tunneling tip;
a MEMS device including a conducting surface opposed the tunneling tip; and
a single layer of C₆₀ fullerene between the tunneling tip and the MEMS device conducting surface.